

## C. Number search - 1/6

- Almost all the Patent & Utility model gazettes issued by the JPO can be searched with any kind of the numbers of gazettes.
  
- Examples of kinds of numbers
  - Application Number
  - Publication Number
  - Patent Number
  - ...

## C. Number search - 2/6

### Number search

• [Patent & Utility Model  
Number Search](#)

**Click!**

**Patent & Utility Model Number Search** [? Help](#)

[Search](#) [List](#) [Detail](#)

You can retrieve a variety of patent and utility model gazettes by their numbers.

Publication issued, and updates schedule, please refer to the [NEWS](#).

#### Document Number

Kind	Document Number
Patent application number	e.g. 2015-00012X 2015-12X H27-00012X
A:Publication of patent application	e.g. 2015-00012X 2015-12X H27-00012X
Patent appeal/trial number	e.g. 2015-00012X 2015-12X H27-00012X

[+ Add](#)

**Search**

[Data Coverage](#)

\* When you input Christian year beginning and a seven or less-digit document number, please input in the form of "2015-12X"

[To return to the top of this page](#)

## C. Number search - 3/6

**Patent & Utility Model Number Search** [? Help](#)

Search → List → Detail

You can retrieve a variety of patent and utility model gazettes by their numbers.

Publication issued, and updates scheduled

**Document Number**

Kind	Document Number
Patent application number	e.g., 2015-00012X 2015-12X H27-00012X
A:Publication of patent application	e.g., 2015-00012X 2015-12X H27-00012X
Patent appeal/trial number	e.g., 2015-00012X 2015-12X H27-00012X

+

 Add

Search

Data Coverage

\* When you input Christian year beginning and a seven or less-digit document number, please input in the form of "2015-12X"

[↑ To return to the top of this page](#)

Kind of number

Document Number

Click "Search"

## C. Number search - 4/6

**Patent & Utility Model Number Search** [Search](#) [List](#) [Detail](#)

You can retrieve a variety of patent and utility model information, including the following:

Publication issued, and unpublished

**Document Number**

Kind	Document Number
Patent application number	e.g., 2015-00012X 2015-12X H27-00012X
A:Publication of patent application	e.g., 2015-00012X 2015-12X H27-00012X
Patent appeal/trial number	e.g., 2015-00012X 2015-12X H27-00012X

[+ Add](#)

[Data Coverage](#)

[To return to the top of this page](#)

\* When you input Christian year beginning and a seven or less-digit document number, please input in the form of "2015-12X"

Select

**"Patent application number"**

**"2002-273006"**

[Search](#)

Click **"Search"**

## C. Number search - 5/6

The search results list is displayed.

Click the publication number **“2004-107736”**.

**Patent & Utility Model Number Search** [Back](#) [? Help](#) [Search](#) → [List](#) → [Detail](#)

You can retrieve a variety of patent and utility model gazettes by their numbers.

**Results**

Display Type ☒ All Pages ☐ Front Page ☐ Claims ☐ Drawings ☒ Specification(unexamined)

Results 1 records.

Number	Application Number	Unexamined Publication Number	Examined Publication Number	Registration Number	Appeal/trial Number	other
1	JP,2002-273006	<a href="#">JP,2004-107736.A</a>	-	<a href="#">JP,4180333.B</a>	-	-

Click **“2004-107736”**

## C. Number search - 6/6

**Selected Gazette**

Patent & Utility Model Number Search

You can retrieve a variety of patent and utility model gazettes by their number.

**Selected Gazette**

JP,2004-107736,A

PAJ Detail Image

Previous Document 1/1 Next Document

Legal Status

(11)Publication number : 2004-107736  
(43)Date of publication of a : 2004.04.28  
(51)Int.Cl. : B01J 23/46

(21)Application number :  
(22)Date of filing : 19.04.2003  
(71)Applicant : UTEC:K  
(72)Inventor : HAYAKAWA

(54)PLASMA CVD SYSTEM AND PLASMA CVD METHOD

(57)Abstract  
PROBLEM TO BE SOLVED: To provide a plasma CVD method in which the damage of plasma is reduced by preventing the exposure of plasma to the substrate.  
SOLUTION: In the plasma CVD system, a DLC (Diamond-Like Carbon) film is deposited on the substrate (substrate 4) to be film-deposited by using a vacuum chamber 1, a substrate holder 2 arranged in the vacuum chamber 1, a substrate 4, and an earth counter electrode 3 arranged in the vacuum chamber 1 as to be confronted with the face on the side reverse to the face on the side of the substrate holder. A gaseous starting material is introduced into the vacuum chamber 1, the vacuum chamber 1 is evacuated, and RF (Radio Frequency) is applied so that plasma 5 is generated between the substrate 4 and the earth counter electrode 3 to deposit a DLC film on the substrate 4.

**Selection of Tab**

- PAJ : Patent Abstract of Japan
- Detail : Full Text (Machine Translation)
- Image : Original Japanese document

**Previous/Next Document**

**Legal Status**

